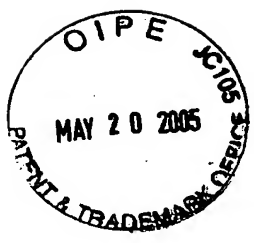


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CERTIFICATE OF MAILING

I hereby certify that this correspondence is being deposited on May 18, 2005 with the United States Postal Service with sufficient postage as first class mail in an envelope addressed to: Mail Stop Amendment, Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

Aimee Harrison
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5/18/05
Date

PATENT
IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Serial No: 10/749,887
Filing Date: December 31, 2003
Art Unit: 1756
Applicant: Dixon et al.
Title: METHOD AND SYSTEM TO COMPENSATE FOR LAMP
INTENSITY DIFFERENCES IN A PHOTOLITHOGRAPHIC
INSPECTION TOOL
Atty Docket: CT-004

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT

Applicant hereby submits the references listed on attached PTO-1449 and calls them to the attention of the Patent and Trademark Office for the above-referenced case. No admission is made that the cited art represents the prior art or that the cited art is the most material art. This application was filed after June 30, 2003, and therefore, no copies are enclosed of the U.S. Patents or Published applications cited as references herein.

I hereby certify that each item of information contained herein was cited for the first time in a communication in a counterpart application from a foreign patent office not more than three months prior to the filing of this Information Disclosure Statement. (37 C.F.R. §1.97(e)(1))

Further, I hereby certify that each item of information contained herein was cited in a communication from a foreign patent office in a counterpart application and that this communication was not received by any individual designated §1.56(c) more than thirty days prior to the filing of this Information Disclosure Statement. (37 C.F.R. §1.704(d))

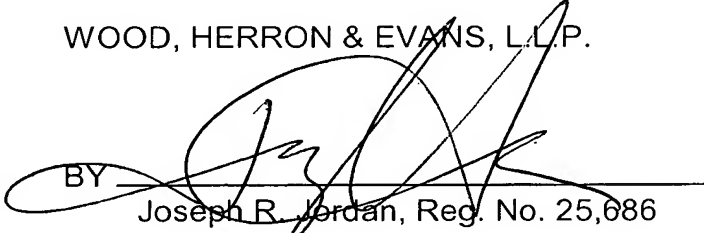
The Examiner is urged to consider the cited references and to make an independent decision with respect to their materiality.

It is submitted that the cited references alone or with the other art of record does not disclose or render obvious that subject matter claimed in the present application.

Applicants do not believe that any fees are due in connection with this submission. However, if such extension is due or any other fees are necessary, the Commissioner may consider this to be a request for such and charge any necessary fees to deposit account 23-3000.

Respectfully submitted,

WOOD, HERRON & EVANS, L.L.P.

BY 
Joseph R. Jordan, Reg. No. 25,686

2700 Carew Tower
Cincinnati, OH 45202
(513) 241-2324
(513) 241-6234 (Facsimile)
jjordan@whepatent.com (Email)

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(MODIFIED)U.S. DEPARTMENT OF COMMERCE
PATENT AND TRADEMARK OFFICEATTY. DOCKET NO.
CT/004SERIAL NO.
10/749,887INFORMATION DISCLOSURE
STATEMENT BY APPLICANTAPPLICANT
Dixon et al.FILING DATE
December 31, 2003GROUP
1756

(37 CFR 1.98(b))

(Use several sheets if necessary)

U.S. PATENT DOCUMENTS

EXAMINER INITIAL		PATENT NUMBER							ISSUE DATE	PATENTEE	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
	A.A	5	2	0	4	9	1	0	4/20/1993	Lebeau			
	A.B												
	A.C												
	A.D												
	A.E												
	A.F												
	A.G												
	A.H												
	A.I												
	A.J												
	A.K												

FOREIGN PATENTS OR PUBLISHED FOREIGN PATENT APPLICATIONS

		DOCUMENT NUMBER	PUBLICATION DATE	COUNTRY OR PATENT OFFICE	CLASS	SUBCLASS	TRANSLATION (YES/NO)
	A.L						
	A.M						
	A.N						
	A.O						
	A.P						
	A.Q						

OTHER DOCUMENTS (Including Author, Title, Date, Place of Publication)

	A.R	Rosengaus et al., Patent Application Publication No. US 2002/O186368 A1, Published Dec. 12, 2002
	A.S	Shibata et al., U.S. Patent Application Publication No. US 2003/O081201 A1, Published May 1, 2003
	A.T	Miller, J.G. et al., Implementing a Fully Automatic Macro Defect Detection and Classification System in a High-Production Semiconductor Fab, Journal of Microlithography, Macrofabrication, and Microsystems, Vol. 2, No. 1, Jan. 2003

EXAMINER

DATE CONSIDERED

EXAMINER: Initial if citation considered, whether or not in conformance. Draw line through citation only if not in conformance and not considered. Include a copy of this form with next communication to applicant.

Substitute Disclosure Form (PTO-1449)